

H-811

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

N. KOFUJI et al

Serial No. 09/363,191

Group Art Unit: 1765

Filed: July 29, 1999

Examiner: V. Perez-Ramos

For: DRY ETCHING APPARATUS AND A METHOD OF  
MANUFACTURING A SEMICONDUCTOR DEVICE

**RESPONSE TO RESTRICTION REQUIREMENT**

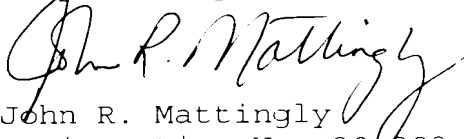
Commissioner of Patents  
Washington, D.C. 20231

Sir:

In response to the Restriction Requirement mailed  
November 6, 2000, applicants elect Group I, Claims 1-20, drawn  
to an etching apparatus, without traverse.

The Commission is hereby authorized to charge any fees  
due in connection with this response to Deposit Account No.  
50-1417.

Respectfully submitted,

  
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